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(12) **United States Design Patent**  
**Jang et al.**

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(54) **SUBSTRATE SUPPORTER FOR SEMICONDUCTOR DEPOSITION APPARATUS**  
(71) Applicant: **ASM IP Holding B.V.**, Almere (NL)  
(72) Inventors: **Hyun Soo Jang**, Daejeon (KR); **Dae Youn Kim**, Daejeon (KR); **Jeong Ho Lee**, Seoul (KR); **Seung Seob Lee**, Seoul (KR); **Hak Yong Kwon**, Osan-si (KR)  
(73) Assignee: **ASM IP Holding B.V.**, Almere (NL)

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(\*\*) Term: **14 Years**

(21) Appl. No.: **29/484,670**

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(51) **LOC (10) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
USPC ..... **D13/182**

(58) **Field of Classification Search**  
USPC ..... D13/182; 118/500, 715, 728, 729;  
156/345.51, 345.52, 345.53, 345.55;  
279/128; 361/234; 414/217, 220.01,  
414/416.03, 935, 936, 937, 938, 939, 940,  
414/941

See application file for complete search history.

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*Primary Examiner* — Elizabeth J Oswecki

(74) *Attorney, Agent, or Firm* — Lexyoume IP Meister, PLLC

(57) **CLAIM**

The ornamental design for a substrate supporter for semiconductor deposition apparatus, as shown and described.

**DESCRIPTION**

FIG. 1 is a perspective view of a substrate supporter for semiconductor deposition apparatus showing our new design;

FIG. 2 is a front elevation view thereof;

FIG. 3 is a rear elevation view thereof;

FIG. 4 is a left side elevation view thereof;

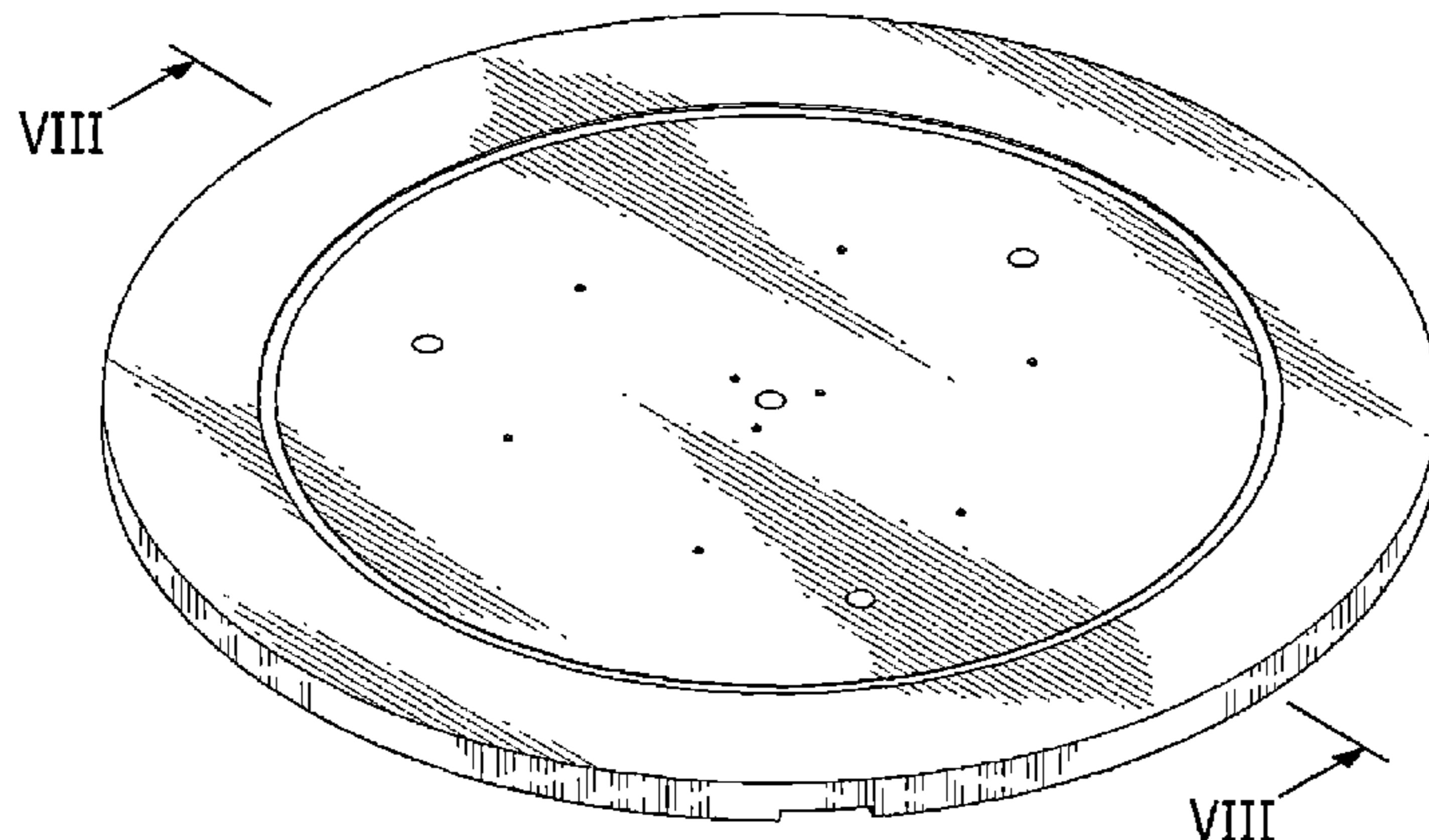
FIG. 5 is a right side elevation view thereof;

FIG. 6 is a top plan view thereof;

FIG. 7 is a bottom plan view thereof; and,

FIG. 8 is a cross-sectional view taken along line VIII-VIII of FIG. 1 with two partially enlarged views showing a transition from a center recess on the top surface of the support and an outer edge at the outer portion of the support.

**1 Claim, 8 Drawing Sheets**



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FIG.1

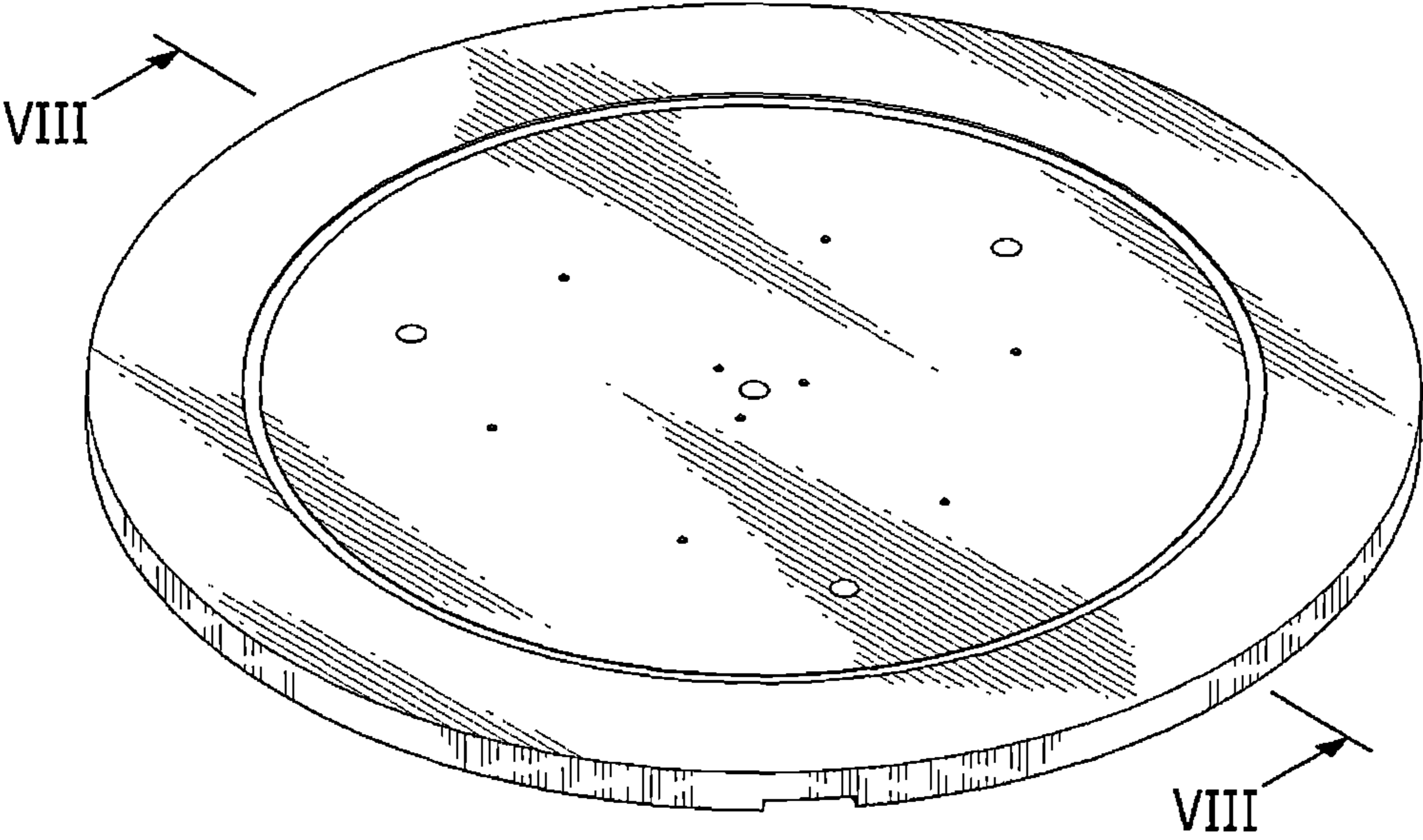


FIG.2



FIG.3



FIG.4



FIG.5



FIG.6

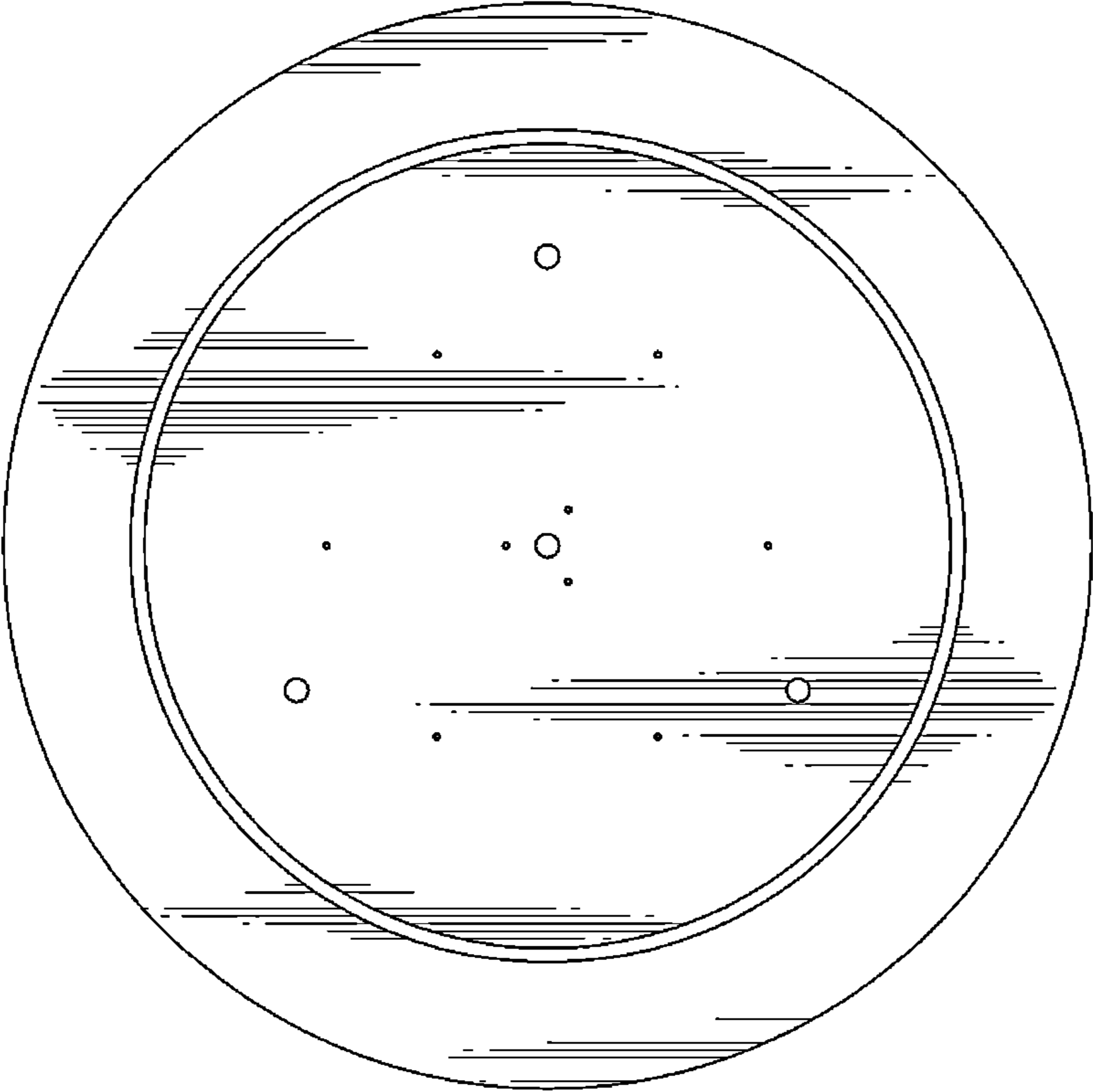




FIG.7

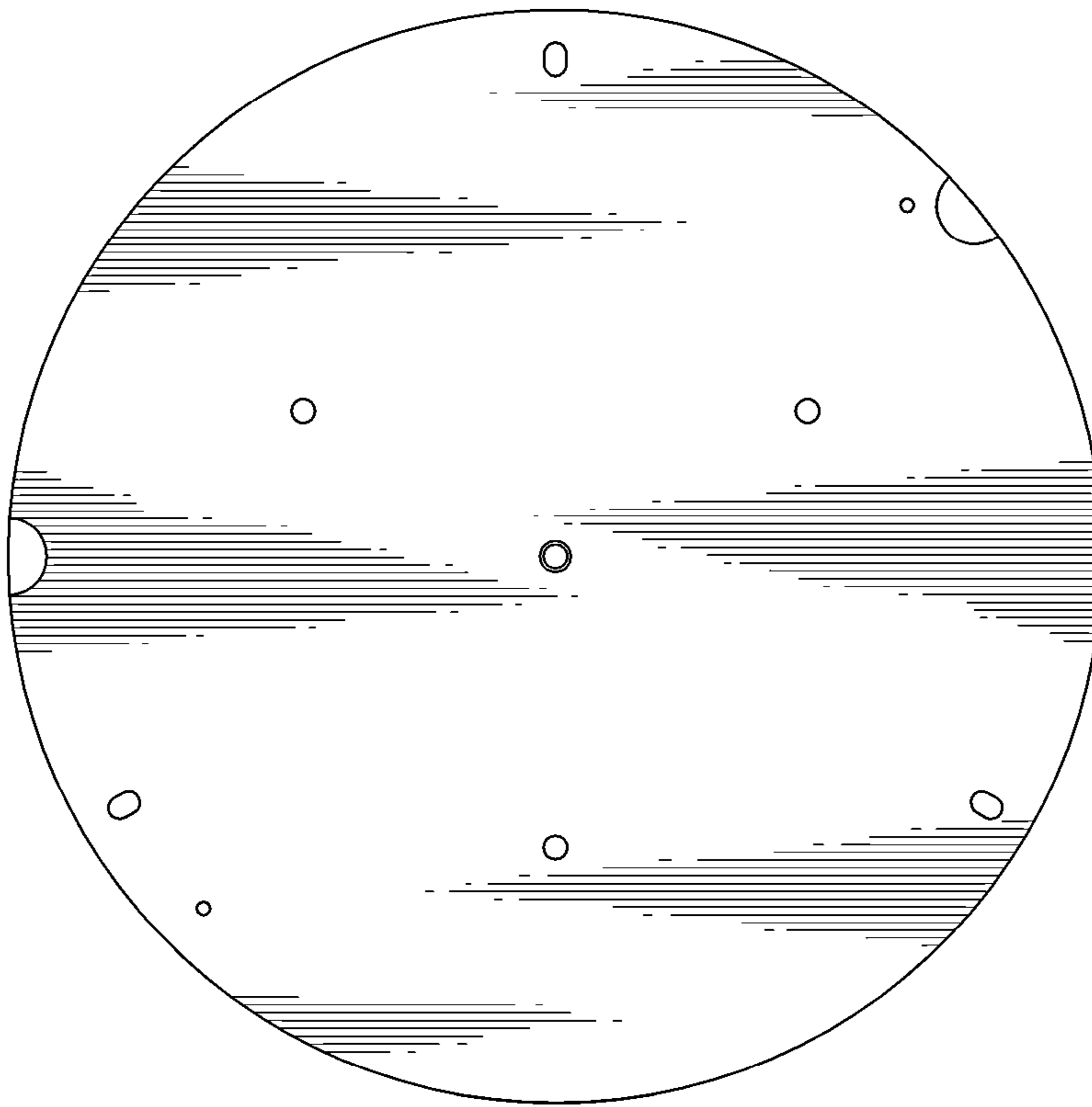


FIG.8

